

Amendments to the Abstract

Please delete the Abstract and replace it with the following:

A method for manufacturing a piezoelectric thin film component wherein a thin titanium film is deposited on a bottom metal layer such that parts of the thin titanium film remain on crystal grain boundaries of the bottom metal layer and form seed crystals. A polycrystalline piezoelectric thin film is formed on the bottom metal layer so that a perovskite crystalline lattice is grown from the seed crystals.